

**ELECTRON TRANSPORT PHENOMENA IN  
SIZE-QUANTIZED n-Ge AND n-Si FILMS**

**G.B. IBRAHIMOV**

*Institute of Physics, Azerbaijan National Academy of Sciences,  
Javid Avenue 33, 370143, Baku, Azerbaijan Republic*

**V.M. HAJIYEV**

*Schlumberger Logelco Inc.,  
Salyan Highway, Shikh District, 370023, Baku, Azerbaijan Republic*

The behavior of some kinetic coefficients depending on *n*-Ge and *n*-Si films surface orientation is investigated in the nonquantized magnetic field. The general solution of transport equation and expressions for the relaxation time at various electron scattering cases are obtained. Also the expressions for halvanomagnetic and thermomagnetic tensors are obtained at the arbitrary degeneration of electron gas. The Hall constant and thermopower of *n*-Ge and *n*-Si films in a strong and weak transverse magnetic field are calculated.

**1. Introduction**

At present thin semiconducting films are intensively investigated in the size-quantized conditions connected with microelectronics development. When the specimen sizes are of de Broglie wavelength of the current carriers' the quantum-sized effects occur and the wave functions form changes. Some thermodynamic and kinetic properties of conducting films with standard zone (simple isotropic model) have been considered in the works [1-4]. In the work [5] the electron states in anisotropic size-quantized *n*-Ge and *n*-Si

films have been considered and the so-called size-quantized anisotropy (dependence of physical values on film surface orientation) was predicted. Evidently, such dependence can be observed in kinetic properties of *n*-Ge and *n*-Si films.

**2. Transport equation**

The energy spectrum of electrons in the size-quantized *n*-Ge and *n*-Si films takes a form:

$$\epsilon_s(n_s, k_x, k_y) = \frac{\hbar^2}{2m_{||}} \left(\frac{\pi}{d}\right)^2 \varphi_s^2(\alpha) n_s^2 + \frac{\hbar^2}{2m_{\perp}} [\varphi_s^{-2}(\alpha) k_x^2 + k_y^2], \tag{1}$$

where  $m_{||}$  and  $m_{\perp}$  are the longitudinal and transverse effective electron masses, respectively;  $d$  is the film thickness,  $s$  is the ellipsoid number,  $n_s=1, 2, 3, \dots$  is the sized quantum number,  $\alpha$  is the angle of rotation of a normal to the [001] film surface around one of the crystallographic axes,  $\varphi_s(\alpha)$  are anisotropy functions characterizing ellipsoids orientation as regard to the system of reference (see [5]).

To consider some kinetic properties of the system it is necessary to solve the Boltzmann transport equation in the external nonquantized magnetic field. The solution of the same equation for *n*-Ge and *n*-Si bulk specimens was obtained in the works [6,7]. In our case of size-quantized *n*-Ge and *n*-Si films we have to solve the two-dimensional transport equation in film's plane.

If one represents the nonequilibrium distribution function of electrons in the form:

$$f_1 = \left( -\frac{\partial f_0}{\partial \epsilon_s} \right) (\vec{v} \vec{P}), \tag{2}$$

and assumes that the external nonquantized magnetic field is directed along a normal to the film surface (transverse field) then the following solution of equation is obtained:

$$\vec{P} = \frac{1}{1+\nu^2} \left\{ \hat{\tau} \vec{\Phi}_0 + \frac{e}{c} \hat{\tau} \left[ \vec{H} \hat{M}^{-1} (\hat{\tau} \vec{\Phi}_0) \right] \right\}, \tag{3}$$

where  $f_0$  is the Fermi-Dirac function,  $\nu = \frac{e|\hat{\tau}|^{1/2}}{c|\hat{M}|^{1/2}} H$ ,

$$\vec{\Phi}_0 = -e\vec{E} - \frac{\epsilon_s - \xi}{k_0 T} k_0 \vec{\nabla} T, \hat{\tau} \text{ is the tensor of relaxation}$$

time,  $\hat{M}^{-1}$  is the inverse tensor of electron effective masses,  $|\hat{\tau}|$  and  $|\hat{M}|$  are determinants of the relaxation time and effective masses tensors, respectively.

As we see from (2) and (3)  $\vec{P}$  like nonequilibrium function depends on components of the relaxation time tensor. Therefore, to calculate the kinetic coefficients it is necessary to obtain the relaxation time expression for different electron scattering cases. In *n*-Ge and *n*-Si films plane  $\vec{P}$  has two components depending on only one relaxation time parameter  $\tau_s$ .

The  $\tau_s$  expression for electrons scattering on acoustical and non-polar optical phonons, point defects and ionized impurities in films plane takes a form:

$$\tau_s^{-1}(\epsilon_s) = \sum_{\beta'_s \beta_s} W_{\beta'_s \beta_s} \left( 1 - \frac{k'_x k_x + \varphi_s^4(\alpha) k'_y k_y}{k_x^2 + \varphi_s^4(\alpha) k_y^2} \right), \quad (4)$$

where  $W_{\beta'_s \beta_s}$  is the probability of electron transition from a  $\beta_s = (n_s, k_x, k_y)$  state to a  $\beta'_s = (n'_s, k'_x, k'_y)$  state and back.

The exact calculations in the cases of electron scattering on phonons and point defects give us:

$$\tau_s(\epsilon_s) = \tau_0 \varphi_s^{-1}(\alpha) \left( \bar{n}_s + \frac{I}{2} \right)^{-1}, \quad (5)$$

where  $\bar{n}_s = \left[ \sqrt{\frac{\epsilon_s}{\epsilon_{I_s}}} \right]$  is an integer part of  $\sqrt{\frac{\epsilon_s}{\epsilon_{I_s}}}$  (the average number of film subbands below energy  $\epsilon_s$ ),  $\epsilon_{I_s} = \epsilon_s$  ( $n_s=1, k_x=k_y=0$ ),  $\tau_0$  is the multiplier that doesn't depend on energy but proportional to the film thickness.

As it is seen from (5)  $\tau_0$  depends on energy only through  $\bar{n}_s$ . Moreover,  $\tau_s$  essentially depends on n-Ge and n-Si films surface orientation and this dependence vanishes only at the  $\bar{n}_s \gg I$  limit when the result for bulk specimen is obtained.

In the case of electrons scattering on ionized impurities the  $\tau_s$  analytical expression for arbitrary  $\bar{n}_s$  values is n't obtained. However, if we assume that the scattering on ionized impurities occurs without the transition between film subbands then the following result for relaxation time is obtained:

$$\tau_s(\epsilon_s) = \tau_0 \varphi_s^{-1}(\alpha) \left( \bar{n}_s + \frac{I}{2} \right)^{-1} \left( \frac{\epsilon_s - \epsilon_{ns}}{k_0 T} \right)^2, \quad (6)$$

where  $\epsilon_{ns}$  is the discrete part of the energy spectrum (1).

### 3. Hall constant and thermopower

Having knowledge of the transport equation solution and expression for the relaxation time one can calculate the current and the energy stream densities and then we can determine components of kinetic tensors. For the  $\sigma_{ik}$  and  $\beta_{ik}$  ( $i, k=1, 2, ; i \leq k$ ) tensors connecting the current and the energy stream densities with the electric field and the temperature gradient the following expressions are obtained:

$$\sigma_{ik} = \frac{e^2 m_{\perp}}{\pi d \hbar^2} \left( -\frac{eH}{c} \right)^{k-i} \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} \int_{\epsilon_{ns}}^{\infty} \frac{(\epsilon_s - \epsilon_{ns}) \left( -\frac{\partial f_0}{\partial \epsilon_s} \right) K_k(\epsilon_s) K_{k-i}(\epsilon_s) d\epsilon_s}{I + v^2(\epsilon_s)} \right\}, \quad (7)$$

$$\beta_{ik} = \frac{em_{\perp}}{\pi d \hbar^2 T} \left( -\frac{eH}{c} \right)^{k-i} \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} \int_{\epsilon_{ns}}^{\infty} \frac{(\epsilon_s - \epsilon_{ns})(\epsilon_s - \xi) \left( -\frac{\partial f_0}{\partial \epsilon_s} \right) K_k(\epsilon_s) K_{k-i}(\epsilon_s) d\epsilon_s}{I + v^2(\epsilon_s)} \right\}, \quad (8)$$

where

$$K_0 = I, K_1(\epsilon_s) = \frac{\tau_s(\epsilon_s) \varphi_s^{-2}(\alpha)}{m_{\perp}}, K_2(\epsilon_s) = \frac{\tau_s(\epsilon_s)}{m_{\perp}},$$

$N=4(n\text{-Ge})$  and  $N=6(n\text{-Si})$ .

On a base of the general expressions (7) and (8) for kinetic tensors we can calculate all kinetic effects in various conditions. Let us show some of them in a strong ( $v \gg 1$ ) and weak ( $v \ll 1$ ) transverse magnetic fields.

So, for the Hall constant in the strong magnetic field we obtain:

$$R_f = -\frac{I}{n_{ef} e c}, \quad (9)$$

where  $n_{ef}$  is the concentration of electrons in film. Therefore, in this case  $R_f$  doesn't depend on the film surface orientation, degree of electron gas degeneration and electron scattering mechanisms. But unlike the bulk specimen  $n_{ef}$  depends on film thickness and this dependence characterizes the quantum-sized effect.

For the thermopower in this case we have:

$$\alpha_f = -\frac{k_0 B(\alpha)}{e A(\alpha)}, \quad (10)$$

where

$$A(\alpha) = \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} F_l(\eta_{ns}) \right\},$$

$$B(\alpha) = \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} [F_2(\eta_{ns}) - \eta_{ns} F_l(\eta_{ns})] \right\}.$$

Here  $F_t(\eta_{ns}) = \int_0^\infty x_s^t \left( -\frac{\partial f_0}{\partial x_s} \right) dx_s$  are the uniparametric

Fermi integrals of  $t$  index,

$$x_s = \frac{\varepsilon_s - \varepsilon_{ns}}{k_0 T}, \eta_{ns} = \frac{\xi - \varepsilon_{ns}}{k_0 T}.$$

The analysis of expression (10) for  $\alpha_f$  shows us that in this case thermopower doesn't depend on scattering mechanisms and for degenerated electron gas we obtain:

$$\alpha_f = -\frac{(\pi k_0)^2 T}{3en_{ef}} g_f(\alpha), \quad (11)$$

where  $g_f(\alpha) = \frac{m_\perp}{\pi d \hbar^2} \sum_{s=1}^N \left\{ \varphi_s(\alpha) \overline{n_s} \right\}$  is the density of electron states in  $n$ -Ge and  $n$ -Si films [5].

Therefore, the  $\alpha_f$  behavior in this case is the same like for the density of electron states near the Fermi energy at the fixed  $n_{ef}$ . Otherwise, the thermopower depends on the film thickness as  $1/d$  until the film subband coincides with the

Fermi energy. In this case  $\alpha_f$  has a leap and is equal to the thermopower value in bulk specimen. Therefore, the thermopower dependence on film thickness has a saw-toothed character.

In another case of nondegenerated electron gas for  $\alpha_f$  we have:

$$\alpha_f = -\frac{k_0}{e} \left\{ 2 - \ln \frac{\pi d \hbar^2 n_{ef}}{m_\perp k_0 TC(\alpha)} + \frac{D(\alpha)}{C(\alpha)} \right\}, \quad (12)$$

where

$$C(\alpha) = \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} \exp(-x_{ns}) \right\},$$

$$D(\alpha) = \sum_{s=1}^N \left\{ \varphi_s(\alpha) \sum_{ns} x_{ns} \exp(-x_{ns}) \right\}, \quad x_{ns} = \frac{\varepsilon_{ns}}{k_0 T}.$$

The  $\alpha_f$  behavior on film thickness in this case differs from the one for degenerated electrons. The analysis of expression (12) shows us that for fixed  $n_{ef}$ . Otherwise, thermopower in this case also is a nonmonotonous function of film thickness.

When  $\overline{n_s} \gg l$  limit the result for bulk specimen is obtained that doesn't depend on a film thickness.

The same kinetic coefficients in the weak magnetic field take forms:

$$R_f = -\frac{I}{n_{ef} e c} \frac{A(\alpha) C'(\alpha)}{A'^2(\alpha)}, \quad (13)$$

$$\alpha_f = -\frac{k_0}{e} \left\{ \frac{D'(\alpha)}{A'(\alpha)} + v_0^2 \left[ \frac{F'(\alpha) C'(\alpha) + B'(\alpha) D'(\alpha)}{A'^2(\alpha)} - \frac{D'(\alpha) C'^2(\alpha)}{A'^3(\alpha)} - \frac{E'(\alpha)}{A'(\alpha)} \right] \right\}, \quad (14)$$

where

$$v_0 = \frac{e \tau_0}{m_\perp c} H, \quad A'(\alpha) = \sum_{s=1}^N \left\{ \frac{[\varphi_s^{-2}(\alpha) + I]}{2} \left( \overline{n_s} + \frac{I}{2} \right)^{-1} \sum_{ns} F_{r+1}(\eta_{ns}) \right\},$$

$$B'(\alpha) = \sum_{s=1}^N \left\{ \frac{[\varphi_s^{-4}(\alpha) + \varphi_s^{-6}(\alpha)]}{2} \left( \overline{n_s} + \frac{I}{2} \right)^{-3} \sum_{ns} F_{3r+1}(\eta_{ns}) \right\},$$

$$D'(\alpha) = \sum_{s=1}^N \left\{ \frac{[\varphi_s^{-2}(\alpha) + I]}{2} \left( \overline{n_s} + \frac{I}{2} \right)^{-1} \sum_{ns} [F_{r+2}(\eta_{ns}) - \eta_{ns} F_{r+1}(\eta_{ns})] \right\},$$

$$E'(\alpha) = \sum_{s=1}^N \left\{ \frac{[\varphi_s^{-4}(\alpha) + \varphi_s^{-6}(\alpha)]}{2} \left( \overline{n_s} + \frac{I}{2} \right)^{-3} \sum_{ns} [F_{3r+2}(\eta_{ns}) - \eta_{ns} F_{3r+1}(\eta_{ns})] \right\},$$

$$F'(\alpha) = \sum_{s=1}^N \left\{ \varphi_s^{-3}(\alpha) \left( \bar{n}_s + \frac{I}{2} \right)^{-2} \sum_{ns} [F_{2r+2}(\eta_{ns}) - \eta_{ns} F_{2r+1}(\eta_{ns})] \right\},$$

$r=0$  for phonons and point defects and  $r=2$  for ionized impurities.

Therefore, in this case unlike the strong field  $R_f$  depends on film surface orientation. Thermopower  $\alpha_f$  depends on magnetic field like small correction proportional  $v_0^2$ .

In conclusion, we note that kinetic coefficients in size-quantized *n*-Ge and *n*-Si films essentially depend on film surface orientation. Therefore, they possess the so-called size-quantized anisotropy. It is the most particular feature of kinetic quantum-sized effects in the anisotropic *n*-Ge and *n*-Si films.

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| [1] <i>V.B. Sandomirsky</i> , J. Eksp. I Teor. Fiziki, 52 (1967) 158 (in Russian).                   | [5] <i>B. Kuliev, V. Hajiyev</i> , Turkish J. of Physics, 22 (1998) 1047.  |
| [2] <i>B.A. Tavger</i> , Physica Status Solidi, 22 (1967) 31.  | [6] <i>B.M. Askerov</i> , Electron Transport Phenomena in Semiconductors, World Scientific, Singapore (1994) 210.                                      |
| [3] <i>B.A. Tavger, V.N. Demikhovskiy</i> , Uspehi Fiz. Nauk, 96 (1968) 61 (in Russian).             | [7] <i>L.I. Baransky</i> , Elektricheskiye I Galvanomagnitniye Yavleniya v Anizotropikh poluprovodnikaxrs, Naukova Dumka, Kiev (1977) 17 (in Russian). |
| [4] <i>B.M. Askerov, B.I. Kuliev, R.F. Eminov</i> , Fizika Nizkih Temp., 33 (1977) 344 (in Russian). |  |

**H.B. İbrahimov, V.M. Hacıyev**

### ***n*-Ge VƏ *n*-Si ÜÇÜN KVANTLANMIŞ NAZİK TƏBƏQƏLƏRDƏ ELEKTRON KEÇİRMƏ HADİSƏLƏRİ**

*n*-Ge və *n*-Si nazik təbəqələrin səthindən asılı olaraq kvantlanmamış maqnit sahəsində kinetik əmsalların xassələri təhlil olunur. Kinetik tənliyin ümumi həlli alınmışdır və müxtəlif elektron səpilmələri üçün relaksasiya zamanı hesablanmışdır. Həmçinin ixtiyari cırılmış elektron qazının qalvanomaqnit və termomaqnit tenzorlar üçün ifadələr alınmışdır. Və nazik təbəqələrdə güclü və zəif eninə maqnit sahəsində Holl əmsalı və termol-EHQ hesablanmışdır.

**Г. Б. Ибрагимов, В.М. Гаджиев**

### **ЭЛЕКТРОННЫЕ ЯВЛЕНИЯ ПЕРЕНОСА В РАЗМЕРНО-КВАНТОВАННЫХ ПЛЕНКАХ *n*-Ge И *n*-Si**

Исследовано поведение некоторых кинетических коэффициентов для размерно-квантованных пленок *n*-Ge и *n*-Si в неквантованном магнитном поле в зависимости от ориентации их поверхности относительно кристаллографических осей. Получено общее решение для кинетического уравнения и выражения для времени релаксации при различных механизмах рассеяния. Также получены выражения для компонент гальваномагнитных и термомагнитных тензоров при произвольном вырождении электронного газа. Вычислены коэффициент Холла и термо-ЭДС для пленок *n*-Ge и *n*-Si в сильных и слабых поперечных магнитных полях.

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